

PATENT ABSTRACTS OF JAPAN

(11) Publication number : **06-241992**

(43) Date of publication of application : **02.09.1994**

(51) Int.CI.

G01N 21/35

(21) Application number : 05-055141

(71) Applicant : SONY CORP

(22) Date of filing : 19.02.1993

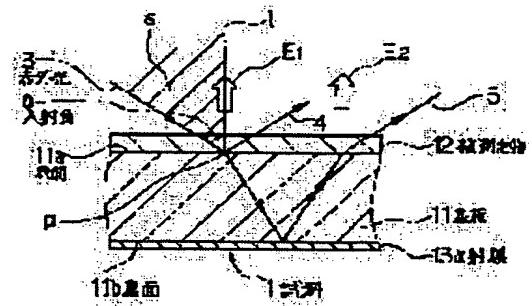
**(72) Inventor : KAWATE YASUTOSHI
SAOTOME NOBUYUKI**

(54) METHOD FOR MEASURING INFRARED REFLECTION SPECTRUM AND ITS SAMPLE

(57) Abstract:

PURPOSE: To provide a method for measuring infrared reflection spectrum which can detect an extremely thin film formed on the surface of a substrate for semi-transmitting infrared light and its sample.

CONSTITUTION: A rear surface 11b of a sample 1 where an object 12 to be measured in thin-film state is formed on a surface 11a of a substrate 11 for transmitting infrared light is polished to mirror-surface state. Then, a reflection film 13 for reflecting infrared light is stuck to the rear surface 11b which is polished to mirror surface. Then, infrared light 3 which is subjected to P polarization is applied to the sample 1 from the side of the object 12 to be measured. Then, the spectra of the infrared rays 4 and 5 which are reflected from the sample 1 are measured. Also, the surface 11a of the substrate 11 is in mirror-surface state.



LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against

examiner's decision of rejection]

[Date of extinction of right]

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